

FIG.1

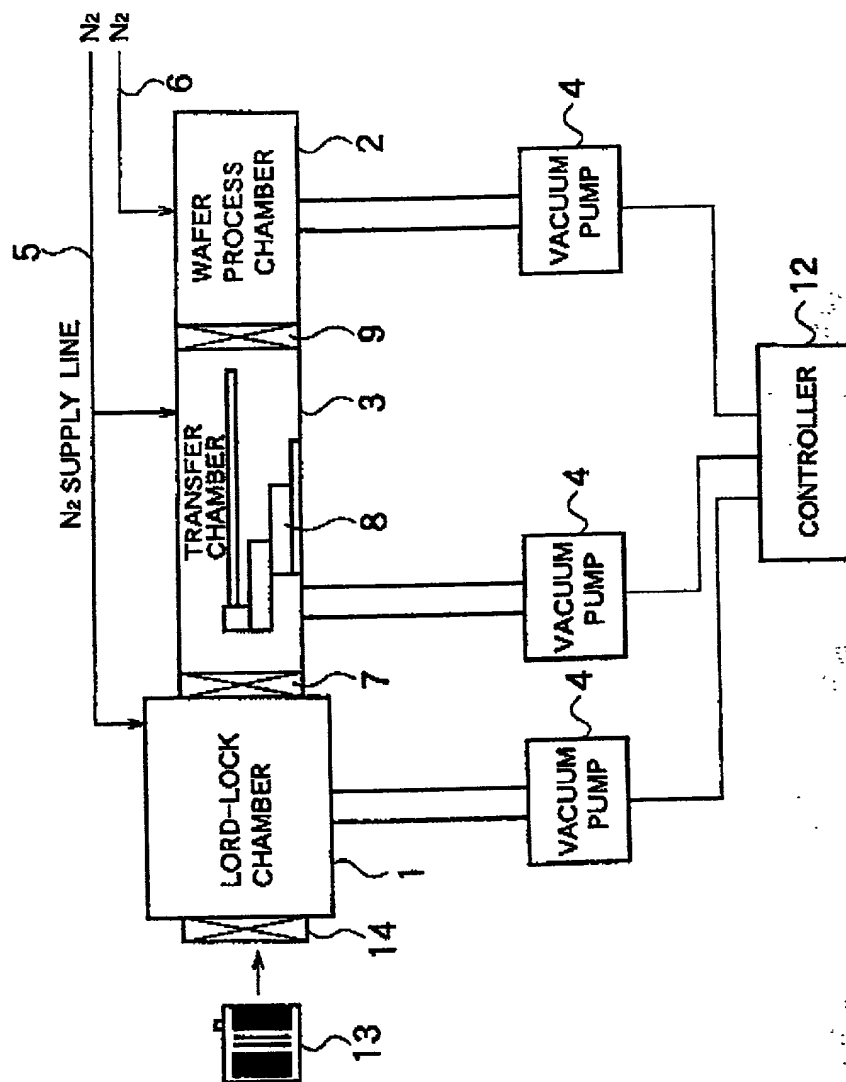


FIG.2

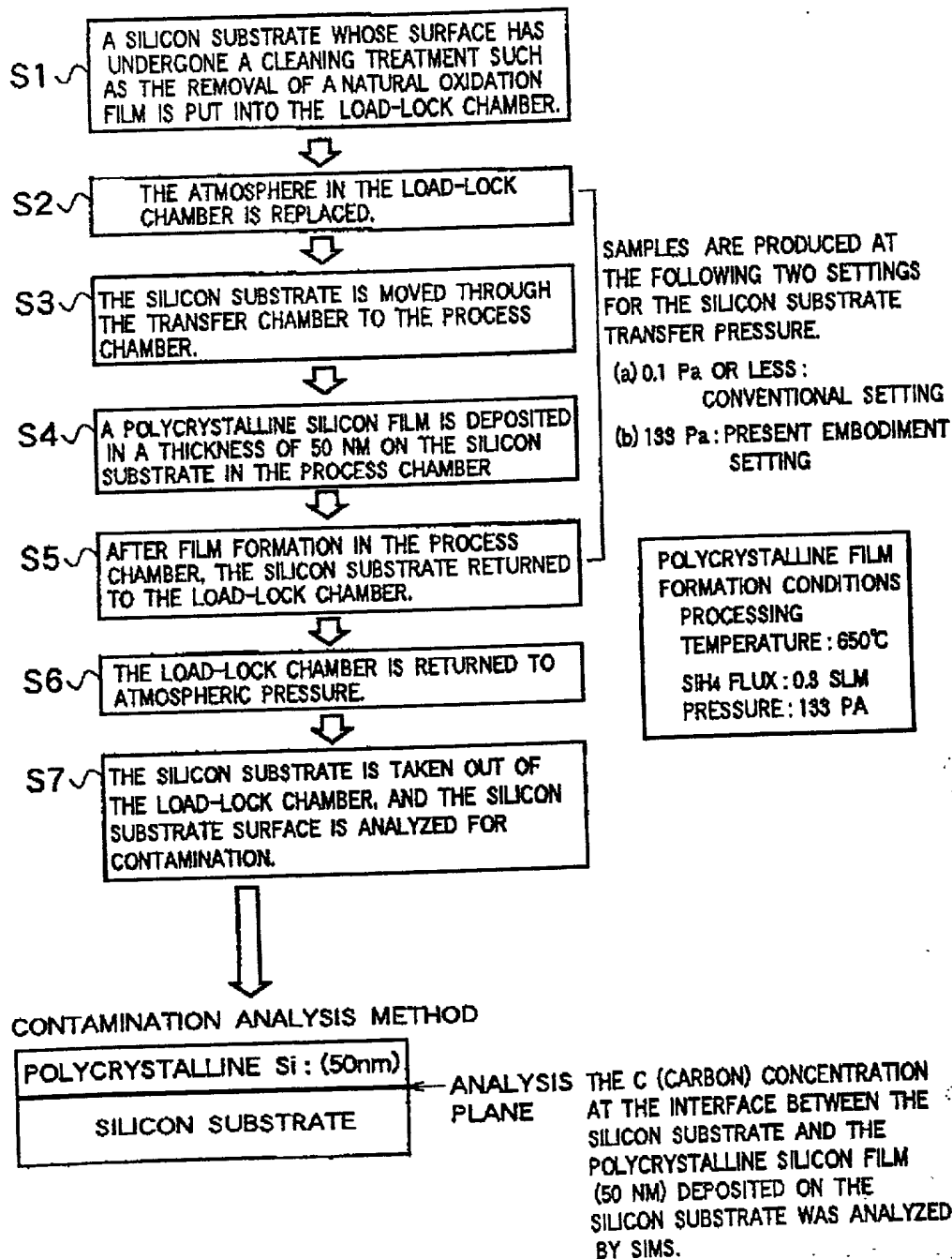


FIG.3

SUBSTRATE TRANSFER PRESSURE		CARBON CONCENTRATION (atoms/cm ²)
(A) CONVENTIONAL SETTING	ATTAINABLE VACUUM TRANSFER 0.1Pa OR LESS	1.90×10^{14}
(B) PRESENT EMBODIMENT SETTING	133Pa	3.70×10^{13}

↓
 5.0×10^{12} atoms/cm²
 (BEST DATA)

FIG.4

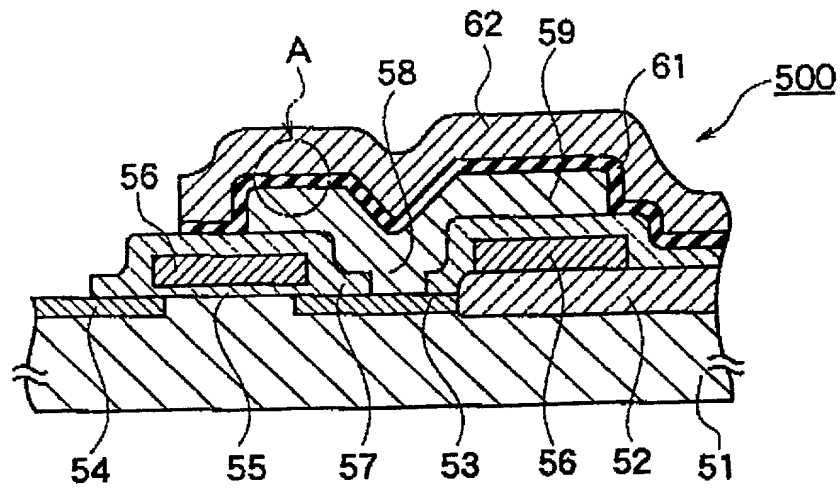


FIG.5

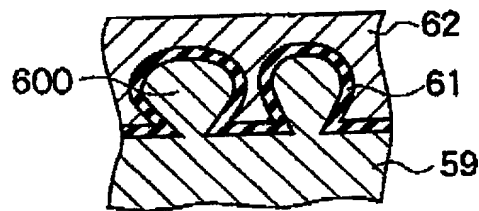
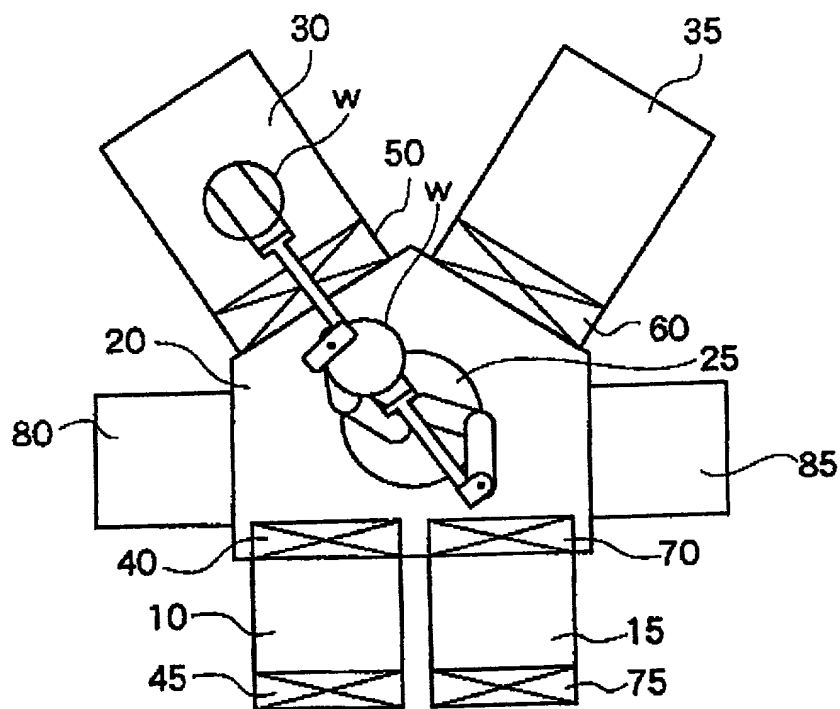


FIG.6



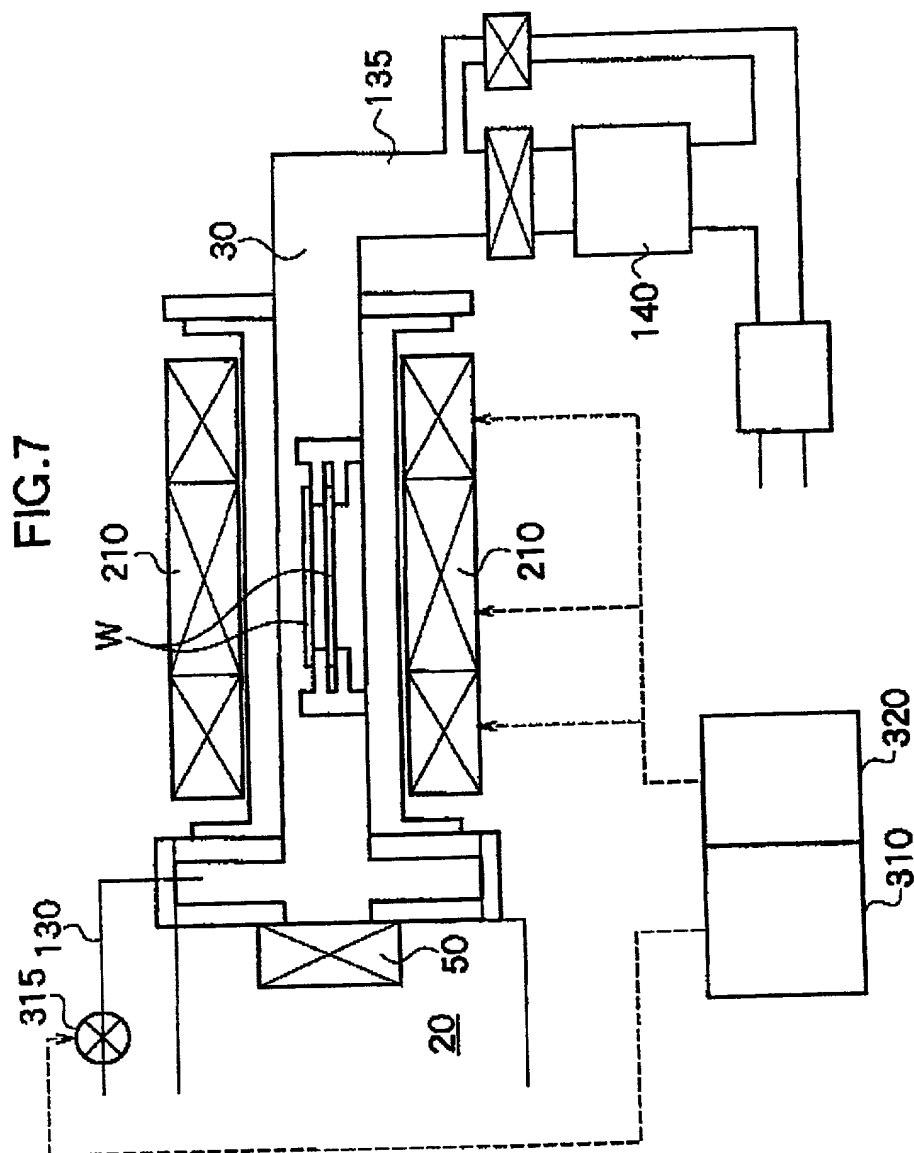
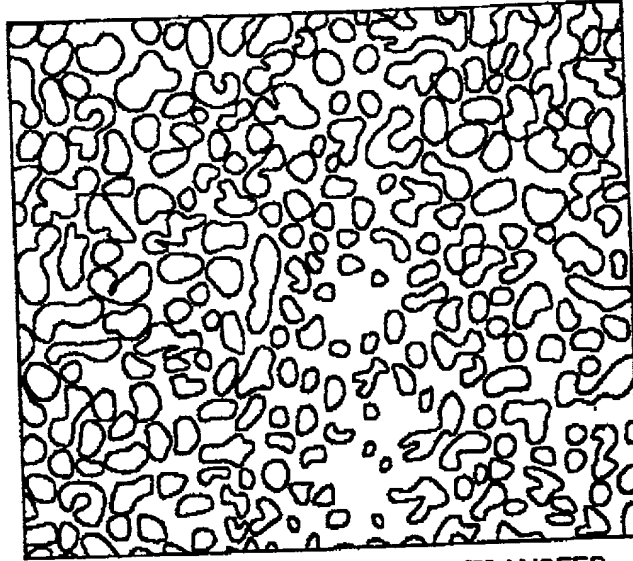
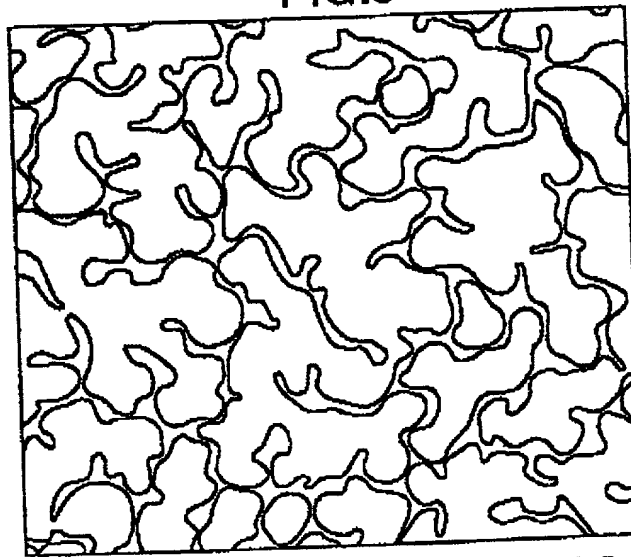


FIG.8



WITH ATTAINABLE VACUUM TRANSFER
INADEQUATE HSG FORMATION
(LACK OF SURFACE BUMPINESS)
DUE TO CONTAMINATION OF
WAFER SURFACE

FIG.9



WITH NITROGEN GAS SUPPLY: 0.5 slm, 50 Pa
ADEQUATE HSG FORMATION (VERY BUMPY SURFACE)